

What is claimed is:

1. An EL display device comprising:
a light emitting layer sandwiched between a cathode and an anode; and
5 a passivation film formed on said anode,
wherein a halogen element is contained in vicinities of an interface between
said light emitting layer and said anode.
2. A device according to claim 1, wherein said halogen element is contained in
10 said anode.
3. A device according to claim 1, wherein said halogen element is contained in
said passivation film.
- 15 4. A device according to claim 1, wherein there are a region containing the
halogen element and a region not containing the halogen element in the vicinities of the
interface between said light emitting layer and said anode.
5. A device according to claim 1, wherein said cathode comprises a metal film
20 containing an alkali metal element or an alkaline earth metal element while said anode
comprises a transparent conductive film.
6. A device according to claim 1, wherein said passivation film is an insulating
film containing silicon.

7. A device comprising an EL display device according to claim 1.

8. An EL display device comprising:

a TFT formed over a substrate;

5 a light emitting layer sandwiched between an anode and a cathode, said cathode electrically connected to said TFT; and

a passivation film is formed on said anode,

wherein a halogen element is contained in vicinities of an interface between said light emitting layer and said anode.

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9. A device according to claim 8, wherein said halogen element is contained in said anode.

10. A device according to claim 8, wherein said halogen element is contained in
15 said passivation film.

11. A device according to claim 8, wherein there are a region containing the halogen element and a region not containing the halogen element in the vicinities of the interface between said light emitting layer and said anode.

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12. A device according to claim 8, wherein said cathode comprises a metal film containing an alkali metal element or an alkaline earth metal element while said anode comprises a transparent conductive film.

25 13. A device according to claim 8, wherein said passivation film is an insulating

film containing silicon.

14. A device comprising an EL display device according to claim 8.

5 15. An EL display device comprising:

a light emitting layer sandwiched between a cathode and an anode; and

a passivation film formed on said anode, and

wherein an alkali metal element or an alkaline earth metal element is
contained in vicinities of an interface between said light emitting layer and said
10 cathode.

16. A device according to claim 15, wherein there are a region containing the
alkali metal element or the alkaline earth metal element and a region not containing the
alkali metal element or the alkaline earth metal element in said passivation film.

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17. A device according to claim 15, wherein there are a region containing the
alkali metal element or the alkaline earth metal element and a region not containing the
alkali metal element or the alkaline earth metal element in the vicinities of the interface
between said light emitting layer and said cathode.

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18. A device according to claim 15, wherein said cathode comprises a metal film
containing an alkali metal element or an alkaline earth metal element while said anode
comprises a transparent conductive film.

25 19. A device according to claim 15, wherein said passivation film is an insulating

film containing silicon.

20. A device comprising an EL display device according to claim 15.

5 21. An EL display device comprising:

a TFT formed over a substrate;

a light emitting layer sandwiched between an anode and a cathode, said cathode electrically connected to said TFT; and

a passivation film is formed on said anode,

10 wherein an alkali metal element or an alkaline earth metal element is contained in vicinities of an interface between said light emitting layer and said cathode.

22. A device according to claim 21, wherein there are a region containing the
15 alkali metal element or the alkaline earth metal element and a region not containing the alkali metal element or the alkaline earth metal element in said passivation film.

23. A device according to claim 21, wherein there are a region containing the alkali metal element or the alkaline earth metal element and a region not containing the
20 alkali metal element or the alkaline earth metal element in the vicinities of the interface between said light emitting layer and said cathode.

24. A device according to claim 21, wherein said cathode comprises a metal film containing an alkali metal element or an alkaline earth metal element while said anode
25 comprises a transparent conductive film.

25. A device according to claim 21, wherein said passivation film is an insulating film containing silicon.

26. A device comprising an EL display device according to claim 21.

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27. A method of manufacturing an EL display device, comprising the steps of:

forming a cathode;

forming a light emitting layer on said cathode;

forming an anode on said light emitting layer;

10 forming a passivation film on said anode; and

doping said light emitting layer with a halogen element through said passivation film.

28. A method according to claim 27, wherein said light emitting layer is doped
15 with the halogen element such that the concentration of the halogen element is the highest in the vicinities of the interface between said anode and said light emitting layer.

29. A method according to claim 27, wherein said cathode is formed of a metal
20 film containing an alkali metal element or an alkaline earth metal element while said anode is formed of a transparent conductive film.

30. A method according to claim 27, wherein said passivation film is formed of an insulating film containing silicon.

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31. A method of manufacturing an EL display device, comprising the steps of:
forming a TFT over a substrate;
forming a cathode that is electrically connected to said TFT;
forming a light emitting layer on said cathode;
5 forming an anode on said light emitting layer;
forming a passivation film on said anode; and
doping said light emitting layer with a halogen element through said
passivation film.

10 32. A method according to claim 31, wherein said light emitting layer is doped
with the halogen element such that the concentration of the halogen element is the
highest in the vicinities of the interface between said anode and said light emitting
layer.

15 33. A method according to claim 31, wherein said cathode is formed of a metal
film containing an alkali metal element or an alkaline earth metal element while said
anode is formed of a transparent conductive film.

20 34. A method according to claim 31 wherein said passivation film is formed of
an insulating film containing silicon.

35. A method of manufacturing an EL display device, comprising the steps of:
forming a cathode;
forming a light emitting layer on said cathode;
25 forming an anode on said light emitting layer;

forming a passivation film on said anode;
selectively forming a resist on said passivation film; and
doping said light emitting layer with a halogen element through said
passivation film.using said resist as a mask.

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36. A method according to claim 35, wherein said light emitting layer is doped
with the halogen element such that the concentration of the halogen element is the
highest in the vicinities of the interface between said anode and said light emitting
layer.

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37. A method according to claim 35, wherein said cathode is formed of a metal
film containing an alkali metal element or an alkaline earth metal element while said
anode is formed of a transparent conductive film.

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38. A method according to claim 35, wherein said passivation film is formed of
an insulating film containing silicon.

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39. A method of manufacturing an EL display device, comprising the steps of:
forming a cathode;
forming a light emitting layer on said cathode;
forming an anode on said light emitting layer;
forming a passivation film on said anode; and
doping said light emitting layer with an alkali metal element or an alkaline
earth metal element through said passivation film.

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40. A method according to claim 39, wherein said light emitting layer is doped with the alkali metal element or the alkaline earth metal element such that the concentration of the alkali metal element or alkaline earth metal element is the highest in the vicinities of the interface between said cathode and said light emitting layer.

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41. A method according to claim 39, wherein said cathode is formed of a metal film containing an alkali metal element or an alkaline earth metal element while said anode is formed of a transparent conductive film.

10 42. A method according to claim 39, wherein said passivation film is formed of an insulating film containing silicon.

43. A method of manufacturing an EL display device, comprising the steps of:

- forming a TFT over a substrate;
- 15 forming a cathode that is electrically connected to said TFT;
- forming a light emitting layer on said cathode;
- forming an anode on said light emitting layer;
- forming a passivation film on said anode; and
- doping said light emitting layer with an alkali metal element or an alkaline
- 20 earth metal element through said passivation film.

44. A method according to claim 43, wherein said light emitting layer is doped with the alkali metal element or the alkaline earth metal element such that the concentration of the alkali metal element or alkaline earth metal element is the highest

25 in the vicinities of the interface between said cathode and said light emitting layer.

45. A method according to claim 43, wherein said cathode is formed of a metal film containing an alkali metal element or an alkaline earth metal element while said anode is formed of a transparent conductive film.

5 46. A method according to claim 43, wherein said passivation film is formed of an insulating film containing silicon.

47. A method of manufacturing an EL display device, comprising the steps of:

- forming a cathode;
- 10 forming a light emitting layer on said cathode;
- forming an anode on said light emitting layer;
- forming a passivation film on said anode;
- selectively forming a resist on said passivation film; and
- doping said light emitting layer with an alkali metal element or an alkaline
- 15 earth metal element through said passivation film using said resist as a mask to dope.

48. A method according to claim 47, wherein said light emitting layer is doped with the alkali metal element or the alkaline earth metal element such that the

20 concentration of the alkali metal element or alkaline earth metal element is the highest in the vicinities of the interface between said cathode and said light emitting layer.

49. A method according to claim 47, wherein said cathode is formed of a metal film containing an alkali metal element or an alkaline earth metal element while said

25 anode is formed of a transparent conductive film.

50. A method according to claim 47, wherein said passivation film is formed of an insulating film containing silicon.